

A Novel Self-Aligned Process to Fabricate High-Index-Contrast Ridge Waveguide Lasers

Di Liang, Jusong Wang and Douglas C. Hall

Dept. of Electrical Engineering, Univ. of Notre Dame, Notre Dame, IN USA 46556-5637;

ABSTRACT

A self-aligned fabrication process for high-index-contrast (HIC) ridge waveguide (RWG) lasers is implemented by combining deep dry etching with O₂-enhanced wet thermal oxidization. The thermal oxide grown on the deeply-etched RWG sidewalls and base provides electrical isolation from the contact metallization resulting in a simplified, self-aligned process. The elimination of a second photolithography step with its potential for alignment error also largely reduces the challenges present in fabricating sub-micron devices with good ohmic contacts by conventional, low-cost photolithography and dry etch processes. The high-quality AlGaAs native oxides, formed by a wet thermal oxidation process modified through the addition of <1% O₂ to the N₂ carrier gas, provide good electrical passivation and a structure which eliminates current spreading. High-power, high-efficiency RWG lasers fabricated in an AlGaAs/InAlGaAs/GaAs graded-index separate confinement heterostructure (GRINSCH) demonstrate the superiority and feasibility of this fabrication process. A native-oxide-defined straight laser (w=7 μm, L= 452 μm) operates cw (300 K, unbonded, p-side up) with a threshold current of I_{th}=21.5 mA (J_{th}=679.5 A/cm²) and slope efficiency of 1.19 A/W (differential quantum efficiency = 78%) at a wavelength of ~813 nm. The resulting HIC semiconductor/oxide interface with Δn~1.7 leads to a high lateral optical confinement factor, enabling curved geometry waveguide devices with bending radii as small as 2 μm in theory. Operation of a half-ring laser having a record small bend radius of 10 μm is demonstrated.

Keywords: high-index-contrast, ridge waveguide laser, thermal oxidation, self-aligned process, surface passivation

Di Liang received his B.S. degree in Optical Engineering from Zhejiang University (Hangzhou, China) in 2002, and M.S. degree in Electrical Engineering from the University of Notre Dame in 2004. His master thesis is on the Silicon-On-Insulator (SOI) single-mode rib waveguide simulation, fabrication and characterization. He is currently working toward his Ph.D. degree in electrical engineering at the University of Notre Dame. His research interests include the study on the thermal oxidation in AlGaAs, the design, simulation and fabrication of low-loss optical waveguides and III-V high-index-contrast lasers.

* dliang@nd.edu, jwang1@nd.edu; phone 1 574 631 9034; fax 1 574 631 4393; xml.ee.nd.edu